Developments of silicon based low temperature detectors

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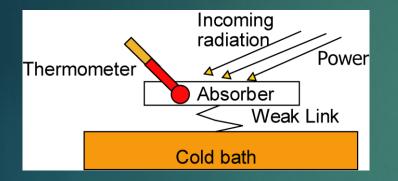
Outline

 Overview of Genoa Low temperature detector group activity

- HOLMES ERC advanced grant (Idea and Goals)
- ATHENA x-ray space mission
- Cosmic Microwave Background spider web detector preliminary development
- A possible contribution to electronic coupling

Thermal detectors: bolometer & calorimeter

Basic idea of this detector

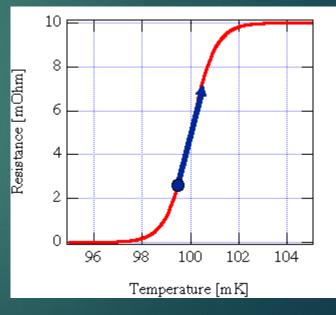


Incoming Radiation (photons, charged particle) or decay of implanted isotopes heats the absorber.

We detect temperature variation.

TES as thermometer

The thermometric element is a superconductor thin film used across its critical temperature



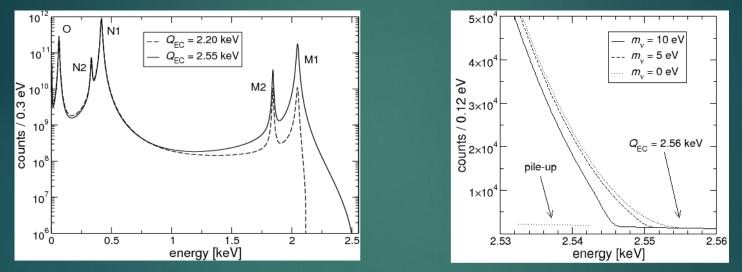
$$\frac{T_0}{R_0}\frac{dR}{dT} > 50$$

HOLMES





The Electron Capture Decay of ¹⁶³Ho to Measure the Electron Neutrino Mass with sub-eV Sensitivity



- A calorimeter can detect all energy of the decay process except neutrino energy
- The deviation from of the spectrum Breit-Wigner at the end point is due to the v mass

In collaboration with

HOLMES Objectives



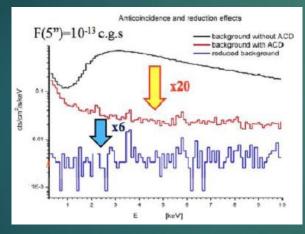


- 1000 detectors based on TES in one array multiplexed
- 1-3 years of data take
- 300 Bq of activity for each detector
- ▶ ∆E ~ 1eV
- Time resolution 1 µs



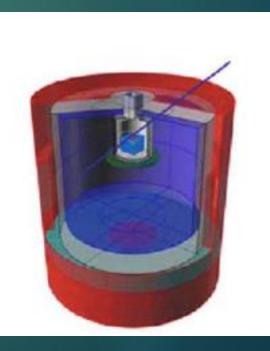
Anti-Coincidence detector for ATHENA x-ray space mission

 Cosmic rays can excite x-ray detectors, producing a large background

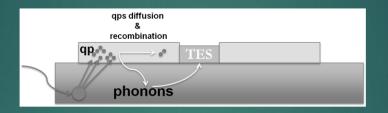


A factor 20 can be performed just using a Anti-Coincidence



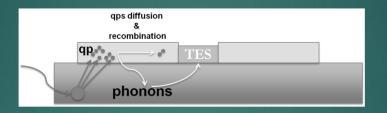


Cryogenic Anti-Coincident concepts



 The absorber is the Silicon substrate Charged particles produce phonons in silicon

Cryogenic Anti-Coincident concepts



- The absorber is the Silicon substrate
- Superconducting thin film is used as collector to increase the rise time
- Charged particles produce phonons in silicon
- Phonons broke Cooper pairs. Quasi particle are collected to the TES

Fabrication process 1: TES & collector

Ir thin film grown (320 nm) by PLD on silicon wafer

Positive Photolithography

Dry etching by ion milling

Al collectors and wiring by negative photolithography and lift-off process (450 nm)

Fabrication process 1: TES & collector

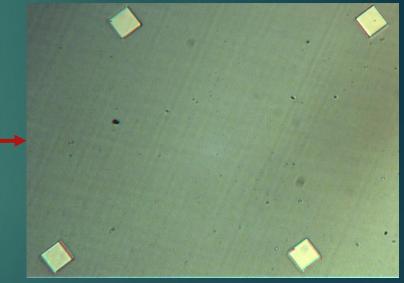
Ir thin film grown (320 nm) by PLD on silicon wafer

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Al collectors and wiring by negative photolithography and lift-off process (450 nm)

65 TES 100x100 μm on 10x10 mm square chip



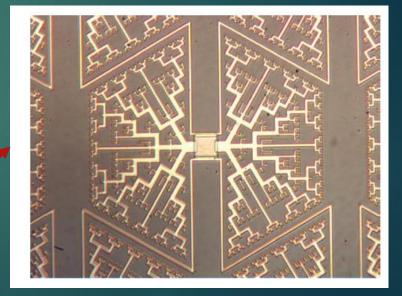
Fabrication process 1: TES & collector

Ir thin film grown (320 nm) by PLD on silicon wafer

Positive Photolithography

Dry etching by ion milling

Al collectors and wiring by negative photolithography and lift-off process (450 nm) 65 TES + AI Collectors on 10x10 mm square chip Parallel wired



Fabrication process 2: Thermal buffer

A second silicon wafer was used as thermal buffer

4 pillars (50 µm high) was built using negative photolithography and permanent SU-8 photoresist

The 2 wafers were jointed

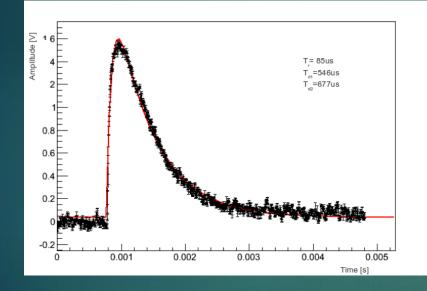
Pillars are the thermal weak link ~ $4x10^{-5}$ W/K



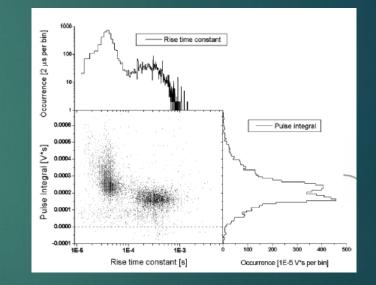


The device at work

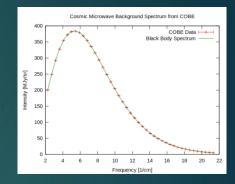
Response to 60 keV γ -ray from ²⁴¹Am source @ 120 mK



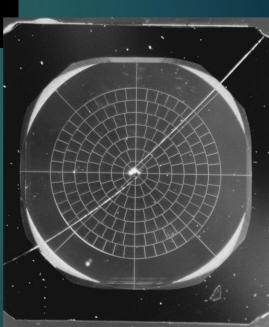
| Rise Time | Decay Time |
|-----------|------------|
| 85 µs | 680 µs |



Cosmic Microwave Background: Spiderweb detectors

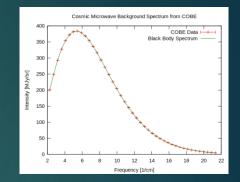


- Blackbody at 2.7 K \rightarrow microwaves with $\lambda \sim 1$ mm
- The cosmic rays coming from the space are a problem also for a microwave bolometer...



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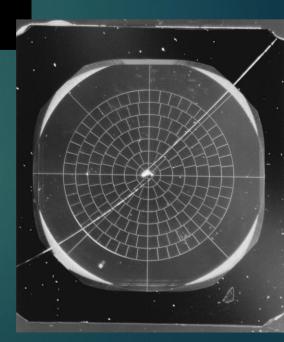
Cosmic Microwave Background: Spiderweb detectors



- Blackbody at 2.7 K \rightarrow microwaves with $\lambda \sim 1$ mm
- The cosmic rays coming from the space are a problem also for a microwave bolometer...

...A grid with a step smaller than $\lambda \setminus 4$ can be equivalent to a filled disk to detect a RF signal.

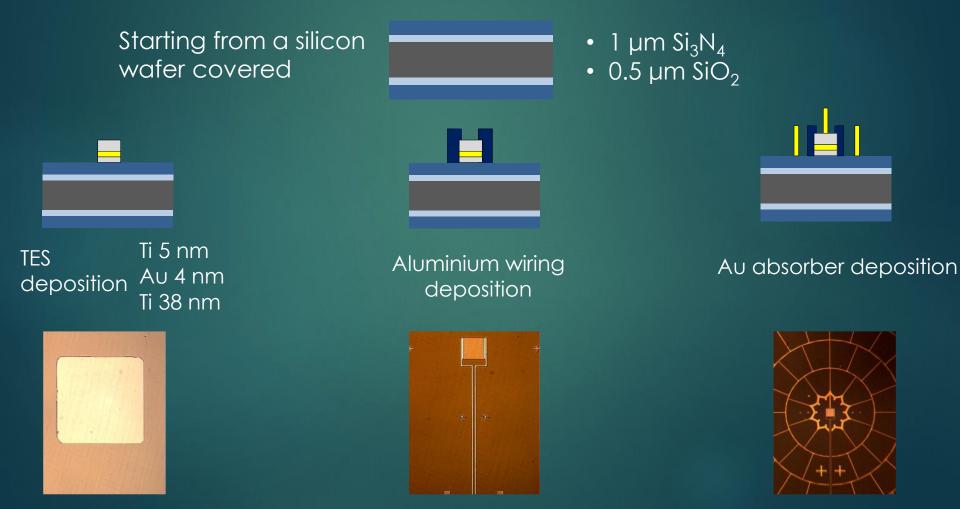
But reduce strongly the surface exposed to the cosmic ray



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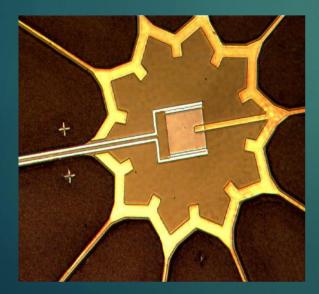
Fabrication Process 1: metals deposition

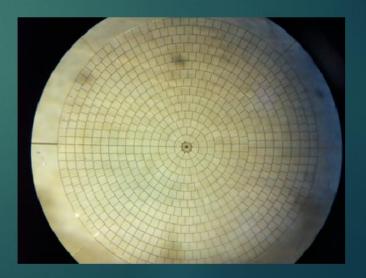
Negative Photolithography, e-beam metal evaporation, Lift-off process



Fabrication Process 2: Etching

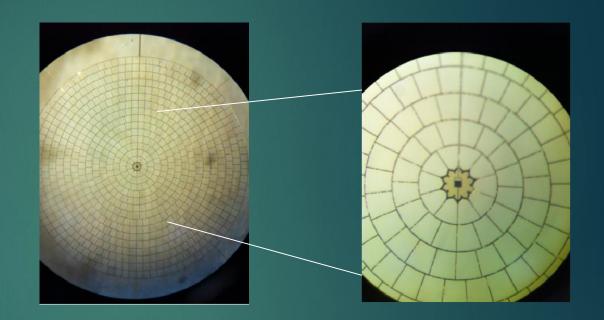
Positive photolithography and RIE CF_4 + O_2 etching RIE back wafer etching with SF₆+O₂ and suspension of spiderweb structure





The final object

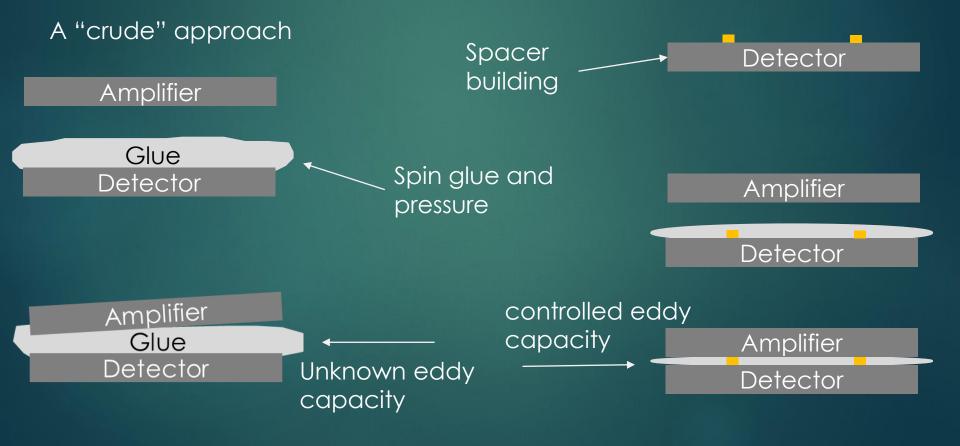




Spiderweb diameter 8 mm Total free standing area 9 mm Square chip side 15 mm

Possible contribution of electronic coupling

Provide uniform capacitive coupling between amplifier and detector chip and safe gluing at the same time.



Pillars built with our micromachining facility

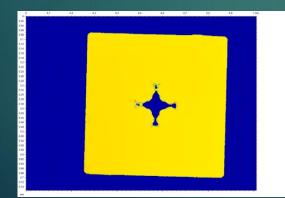
Preliminary test with already available materials (old SU-8 resit, litho-mask and silicon wafers)

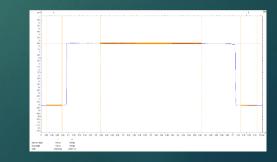


| Pillar 1 | 5.92 |
|----------|------|
| Pillar 2 | 6.07 |
| Pillar 3 | 5.92 |
| Pillar 4 | 5.92 |

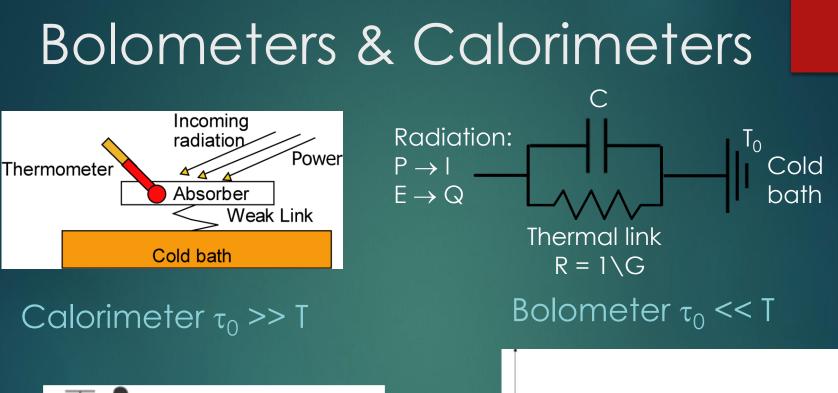
< 0.1 µm height error on a single pilar

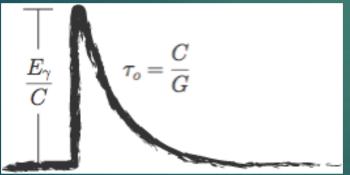
4 mm distance between two pillars

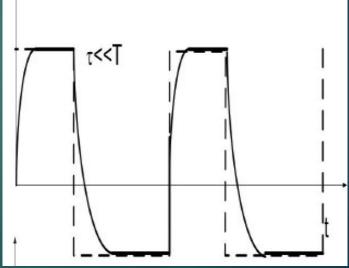




Thank you for attention







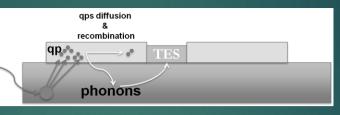
Conclusions

Our

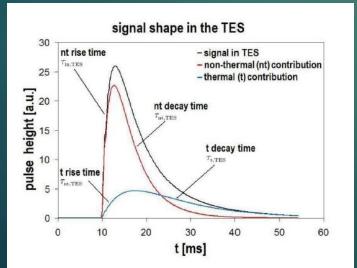
A Spiderweb bolometer for CMB has been shown with its fabrication process.

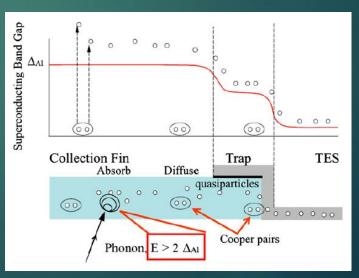
Cryogenic Anti-Coincident

concepts



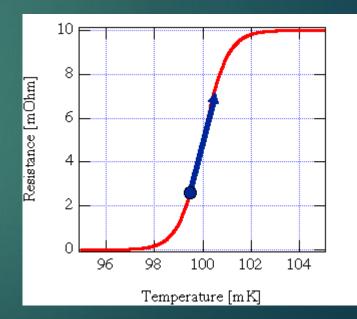
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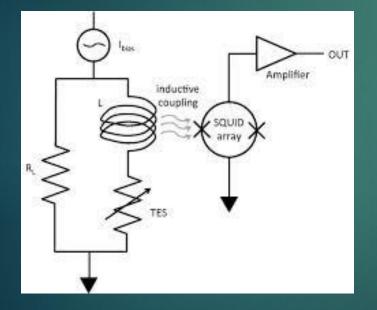




Typical TES readout

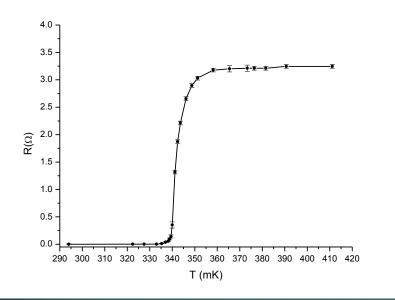
TESs are polarized in applying a tension The signal is read in current using a SQUID as magnetometer TES positive R(T) slope produce e negative electro-thermal feedback that increase its stability





Preliminary characterization of Spiderweb detector

R(T) transition curve



I-V curves

